

Daftar Pustaka

- Ban, C., He, Y., Shao, X., & Du, J. (2013). *Effect of pretreatment on electrochemical etching behavior of Al foil in HCl-H₂SO₄*. Transactions of Nonferrous Metals Society of China, 23(4), 1039–1045. [http://doi.org/10.1016/S1003-6326\(13\)62564-9](http://doi.org/10.1016/S1003-6326(13)62564-9)
- By, W., Henry, B., & Rawdon, S. (n.d.). stances and, (3) on thermal radiophonic signalling apparatus., (398).
- Çakir, O. (2008). *Chemical etching of aluminium*. Journal of Materials Processing Technology, 199, 337–340. <http://doi.org/10.1016/j.jmatprotec.2007.08.012>
- Datta, Madhav. (2002). *Micromachining by Electrochemical Dissolution*. IBM Corporation, Yorktown Height, New York. Micromachining of Engineering Materials *Edited by* McGeough, Joseph, New York. 239-246.
- <http://aluminium-foil.blogspot.com/2013/09/pengertian-aluminium.html/m=1>, diakses pada tanggal 5 november 2014.
- Hu, G., Zhang, H., Di, W., & Zhao, T. (2004). *Study on Wet Etching of AAO Template*. Carbon Nanotubes, 1(2), 78–82. <http://doi.org/10.5539/apr.v1n2P78>
- Lin, W., Tu, G. C., Lin, C. F., & Peng, Y. M. (1996). *The effect of lead impurity on the DC-etching behaviour of aluminum foil for electrolytic capacitor usage*. Corrosion Science, 38(9), 889–907. [http://doi.org/10.1016/0010-938X\(96\)00175-8](http://doi.org/10.1016/0010-938X(96)00175-8)
- Nathan, A. (2005). Nanoelectronics, Winter 2005. E&CE 493 Topic 2/730 Topic 13.
- Pennathur, S. (2010). *The MEMS Class Introduction to MEMS and MEMS Design*. UCSB Nano Lab, The University of California, USA.